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AG 2877  
PATENT  
JFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Inventors: Michael Weber-Grabau et al.

Application No.: 09/927,102

Filed: August 10, 2001

For: CRITICAL DIMENSION METROLOGY  
SYSTEM INTEGRATED INTO  
SEMICONDUCTOR WAFER PROCESS  
TOOL

Group Art Unit: 2877

Examiner: R.R. Rosenberger

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APPLICATION (37 CFR 1.8(a))**

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